



MEMS/NEMS Sensors and Actuators

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Deadline for manuscript
submissions:

closed (28 February 2022)

Message from the Guest Editors

After the rise of MEMS/NEMS devices in the 1970s, the field of MEMS/NEMS sensors and actuators has grown immensely. Beginning in the 21st century, MEMS/NEMS sensors and actuators have been industrialized and applied not only to consumer markets such as mobile phones and games, but also to intelligent manufacturing, robots, aerospace and other fields. Compared with traditional machinery, MEMS/NEMS technology has the characteristics of being miniaturized, intelligent, multifunctional, highly integrated and suitable for mass-manufacturing processes.

This Special Issue seeks to showcase research papers, communications, and review articles that focus on: (1) Novel structural designs of MEMS/NEMS sensors and actuators, (2) Improved fabrication, packaging process and circuit design based on all kinds of MEMS/NEMS products, (3) New sensitive materials committed to a wider range of applications, such as polysilicon, graphene, carbon nanotubes, etc., (4) New developments of applying MEMS/NEMS sensors and actuators including, but are not limited to, MEMS/NEMS pressure sensors, accelerometers, gyroscopes and microphones with capacitive, resonant, piezoelectric and piezoresistive mechanism.





Editor-in-Chief

Message from the Editor-in-Chief

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